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U.S. DEPARTMENT OF COMMERCE
PATENT AND TRADEMARK OFFICEINFORMATION DISCLOSURE
STATEMENTDocket Number
10191/4133Application Number
To Be AssignedFiling Date
HerewithExaminer
To Be AssignedArt Unit
To Be AssignedInvention Title
METHOD AND MICROMECHANICAL
COMPONENTInventor(s)
LAMMEL et al.Commissioner for Patents
P.O. Box 1450
Alexandria, VA 22313-1450

1. In accordance with the duty of disclosure under 37 C.F.R. § 1.56 and in conformance with the procedures of 37 C.F.R. §§ 1.97 and 1.98 and M.P.E.P. § 609, attorneys for Applicants hereby bring the following references to the attention of the Examiner. The references are listed on the attached modified PTO form 1449. It is respectfully requested that the information be expressly considered during the prosecution of this application, and that the references be made of record therein and appear among the "References Cited" on any patent to issue therefrom.
2. A copy of each patent, publication or other information listed on the modified PTO form 1449 is enclosed, except as otherwise indicated on the modified PTO form 1449.

Dated: 3/23/05By: Richard L. MayerBy: LS Magent (Reg. No. 41,172)
Richard L. Mayer (Reg. No. 22,490)KENYON & KENYON
One Broadway
New York, N.Y. 10004
(212) 425-7200 (telephone)
(212) 425-5288 (facsimile)

<p align="center">INFORMATION DISCLOSURE STATEMENT BY APPLICANTS PTO FORM 1449</p>	<p>Atty. Docket No. 10191/4133</p>	<p>Serial No. 10/529425 To Be Assigned</p>
	<p>Applicant(s) LAMMEL et al.</p>	
	<p>Filing Date Herewith</p>	<p>Group To Be Assigned</p>

U. S. PATENT DOCUMENTS

EXAMINER'S INITIALS	PATENT NUMBER	PATENT DATE	NAME	CLASS	SUBCLASS	FILING DATE
	5,542,558*	Aug. 6, 1996	OFFENBERG et al.			
	5,594,171*	Jan. 14, 1997	IMAEDA et al.			

* Copy of reference is not enclosed because reference is cited in Search Report (copy of reference provided by International Searching Authority).

FOREIGN PATENT DOCUMENTS

EXAMINER'S INITIALS	DOCUMENT NUMBER	DATE	COUNTRY	CLASS	SUB-CLASS	TRANSLATION	
						YES	NO
	02 051741*	Jul. 4, 2002	PCT				
	1 088 785*	Apr. 4, 2001	Europe				
	0 895 276*	Feb. 3, 1999	Europe				

* Copy of reference is not enclosed because reference is cited in Search Report (copy of reference provided by International Searching Authority).

OTHER DOCUMENTS

EXAMINER'S INITIALS	AUTHOR, TITLE, DATE, PERTINENT PAGES, ETC.
	Lee et al., <i>A New Wide-Dimensional Freestanding Microstructure Fabrication Technology Using Laterally Formed Porous Silicon as a Sacrificial Layer</i> , Sensors and Actuators, Lausanne, Switzerland, Vol. 84, No. 1-2, Aug. 1, 2000, pgs. 181-5.*
	Splinter et al., <i>Thick Porous Silicon Formation Using Implanted Mask Technology</i> , Sensors and Actuators, Lausanne, Switzerland, Vol. 76, No. 1-3, pgs. June 1, 2001, 354-60.*

* Copy of reference is not enclosed because reference is cited in Search Report (copy of reference provided by International Searching Authority).

EXAMINER	DATE CONSIDERED
<p>EXAMINER: Initial if citation considered, whether or not citation is in conformance with M.P.E.P. 609; draw line through citation if not in conformance and not considered. Include copy of this form with next communication to applicant.</p>	

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